Abstract

According to the invention, a transport system is provided for transporting products to be machined, in particular integrated semiconductor products, to machining plants arranged in a building, for carrying out machining steps on the products to be machined. The transport system according to the invention is defined in that the transport system and the machining plants are separated by a building ceiling and feeds from the transport system to the machining plants through orifices in the building ceiling are provided.

The advantage of the transport system according to the invention is that it is separated from the machining plants by virtue of construction. A markedly higher transport speed can thereby be achieved. Each position on the level of the transport system can be reached in a freely selectable way and is accessible any time, should a fault occur. Furthermore, the complexity of the control software can be markedly reduced.

FIG. 1

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